Lambda Design Rules

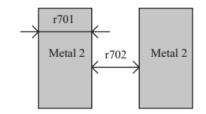
n-Well		DIO.
r101	Minimum well size 12λ	R101 R101
r102	Between wells 12λ	
r110	Minimum well area 144 λ^2	L
		n-well
Diffusion		<u></u>
r201	Minimum N+ and P+ diffusion wie	lth 4 λ Nwell Polarization
r202	Between two P+ and N+ diffusion	4 λ
r203	Extra nwell after P+ diffusion:	6 λ r 203 r 202 r 205
r204:	Between N+ diffusion and nwell	6 λ P+ diff P+ diff
r205	Border of well after N+ polarization	
r206	Between N+ and P+ polarization	0λ representation r^{201} representation r^{206} representation r^{201} representation r^{200} representation
r207	Border of Nwell for P+ polarization	n 6 λ r204 r207
r210	Minimum diffusion area	$24 \lambda^2$
		N+ diff
Polysilicon		P+ polarization
r301	Polysilicon width 2λ	1200
r302	Polysilicon gate on diffusion 2λ	r305
r303	Polysilicon gate on	P+ diff
	diffusion for high	r306
20.4	voltage MOS 4λ	r302
r304	Between two poly silicon boxes 3 λ	r304
r305	Polysilicon vs.	r301
1303	other diffusion 2λ	r303
r306	Diffusion after	r306
	polysilicon 4 λ	N+ diff
r307	Extra gate after	207
	polysilicon 3 λ	r307
r310	Minimum surface $8 \lambda^2$	High voltage MOS

A.2.1 Second Polysilicon Design Rules Poly2 r311 Polysilicon2 width 2λ r312 Polysilicon2 gate on diffusion 2 λ Polysilicon2 minimum surface $8 \lambda^2$ r320 r312 MOS Option rOpt Border of "option" layer over diff N+ and diff P+ 7λ N+dif r404 Contact r401 Contact width 2λ r402 5λ r402 Between two contacts r401 r403 Extra diffusion over contact 2λ Polysilicium Contact r404 2λ Extra poly over contact r405 Contact r405 Extra metal over contact 2λ r403 r406 Distance between contact 3λ and poly gate r406 Diffusion Metal r407 Extra poly2 over contact 2λ Gate Metal 1 r501 4λ r501 Metal width Metal Metal r502 r502 Between two metals 4λ $16 \lambda^2$ Minimum surface r510 r604 Via r602 r601 Via width 2λ via 5λ r602 Between two Via Stacked via over Metal 2 contact when r603 Between Via and contact 0 λ r603 is 0 r603 r604 Extra metal over via 2λ Contact Extra metal 2 over via: 2λ r605

Metal 2

r701	Metal width:	4 λ
r702	Between two metal 2	4 λ

r710 Minimum surface $16 \lambda^2$



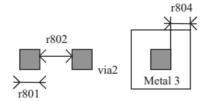
Via 2

r801	Via2	width:	2λ

r802 Between two via2: 5 λ

r804 Extra metal 2 over via2: 2 λ

r805 Extra metal 3 over via2: 2 λ

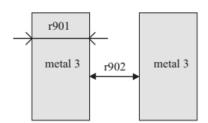


Metal 3

r901 Metal 3 width: 4 λ

r902 Between two metal 3: 4 λ

r910 Minimum surface: $32 \lambda^2$



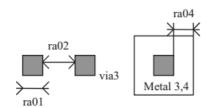
Via 3

ra01 Via3 width: 2 λ

ra02 Between two via3: 5 λ

ra04 Extra metal 3 over via3: 2 λ

ra05 Extra metal 4 over via3: 2 λ

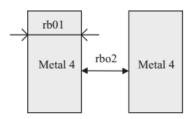


Metal 4

rb01 Metal 4 width: 4 λ

rb02 Between two metal 4: 4 λ

rb10 Minimum surface: 32 λ²



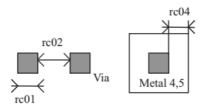
Via 4

rc01 Via4 width: 2 λ

rc02 Between two via4: 5 λ

rc04 Extra metal 4 over via2: 3 λ

rc05 Extra metal 5 over via2: 3 λ

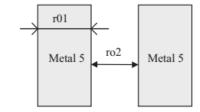


Metal 5

rd01 Metal 5 width: 8 λ

rd02 Between two metal 5: 8λ

rd10 Minimum surface: $100 \lambda^2$



Via 5

re01 Via5 width: 4 λ

re02 Between two via5: 6 λ

re04 Extra metal 5 over via5: 3 λ

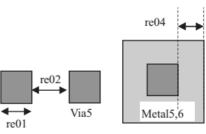
re05 Extra metal 6 over via5: 3 λ

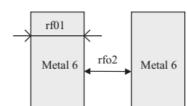
Metal 6

rf01 Metal 6 width: 8 λ

rf02 Between two metal 6: 15 λ

rf10 Minimum surface: $300 \lambda^2$





A.3 Pads

The rules are presented below in μm . In .RUL files, the rules are given in lambda. As the pad size has an almost constant value in μm , each technology gives its own value in λ .

rp01	Pad width:	100 μm	
rp02	Between two pads	100 μm	rp03
rp03	Opening in passivation v.s via:	5 μm	PAD rp02
rp04	Opening in passivation v.s metals:	5 μm	
rp05	Between pad and unrelated active area:	20 μm	rp01